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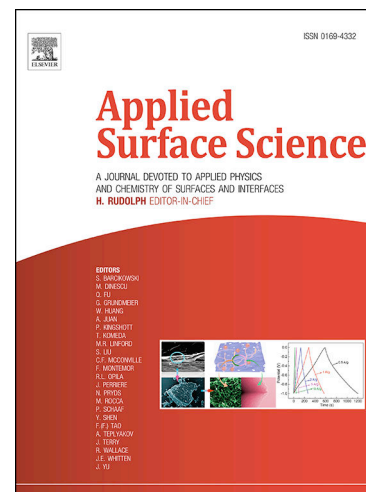
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**Engineered SnO<sub>2</sub>-based thin films for efficient CO<sub>2</sub> gas sensing at room temperature**

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**Abstract**

Tin oxide (SnO<sub>2</sub>)-based thin films were deposited on alumina printed circuit boards via electron beam evaporation to fabricate CO<sub>2</sub> gas sensors operating at room temperature. Femtosecond laser surface nanotexturing was applied as a novel approach to optimize key gas sensitivity parameters, including surface roughness and grain size. Raman and X-ray photoelectron spectroscopy revealed that the sensitive layer consists of a 1 μm SnO film with a non-stoichiometric SnO<sub>2</sub> upper layer for the as-deposited film. The electronic disparity between these layers forms a native SnO-SnO<sub>2</sub> interface, creating a p-n junction that enhances sensor sensitivity. This sensor shows a sensing response ranging from 7% to 20% for CO<sub>2</sub> concentrations of 1000 to 2000 ppm, and up to 40% at 5000 ppm. Laser irradiation introduced periodic surface structures (~ 800 nm), increasing the roughness and the number of active sites for the gas sensing. Although no significant improvements were observed in terms of sensitivity, the fs-laser treated sensor exhibited enhanced stability and reproducibility, indicating its potential for low-energy consumption gas sensing platforms for indoor air quality applications.

**Keywords:** Gas sensor, Carbon dioxide, tin-oxide, LIPSS, surface nanotexturing, MOX

**Introduction**

In recent years, the demand for energy-efficient and sensitive gas sensors has increased, driven by the need to monitor environmental and human health [1]. Common air pollutants include particulate matter and gases such as ozone (O<sub>3</sub>), nitrogen dioxide (NO<sub>2</sub>), sulphur dioxide (SO<sub>2</sub>), volatile organic compounds (VOCs), carbon mono/di-oxides (CO, CO<sub>2</sub>) [2,3].

While monitoring potentially harmful gases in urban areas is essential, it is even more critical in indoor environments such as homes, schools, and offices, where their concentrations can be 2-5 times higher than outdoor levels and people spend approximately 90% of their time [4].

Among various sensor technologies, Metal Oxide Semiconductor (MOX) gas sensors have garnered significant attention. MOX sensors, a type of chemiresistor, operate by changing their electrical resistance when exposed to a target gas. This easy operating principle enables excellent performance at a low cost. [5,6]. Among the different MOX tested as active sensing material, tin dioxide ( $\text{SnO}_2$ ) thin films, in particular, have been extensively researched due to their numerous advantages, including high sensitivity, rapid response and recovery times, cost-effectiveness, and wide availability [7-12]. However, a drawback of  $\text{SnO}_2$ -based sensors is their high operating temperatures, typically between 250-400 °C, required for optimal performance. Operating at such temperatures, especially in real-time gas monitoring, significantly increases energy consumption, complexity of the electronic conditioning, and accelerates device degradation, necessitating frequent maintenance and incurring additional expenses [13-15].

It is reasonable to consider addressing the requirement of operating temperature reduction by enhancing also the sensor's performance in terms of sensitivity and selectivity. To this end, recent research has explored several strategies; first of all, take advantage of the low-dimensional materials properties in order to exploit the excellent surface-volume ratio and maximize the useful surface for the interaction with the gas [10,16-19]. Another approach involves doping which, contributing to a significant increase in the concentration of oxygen vacancies, increases the active sites where adsorption and reaction with the target gas can occur [20]. Examples of doped  $\text{SnO}_2$ -based gas sensors operating at RT are recently reported [21-24]. Another strategy involves the use of composite and multilayer materials that form p-n heterojunctions, enhancing charge transfer rates to improve gas sensitivity. Systems incorporating a p-type semiconductor with n- $\text{SnO}_2$  fall into this category, as reported in various studies [25-27]. These structures aim to achieve both low operating temperatures and high performance (e.g., high sensitivity and fast response), although the technological complexity of these approaches makes them challenging to implement on a large scale, leading to a shortage of  $\text{SnO}_2$ -based systems capable of detecting  $\text{CO}_2$  at room temperature. The following Table 1 presents recent  $\text{SnO}_2$ -based  $\text{CO}_2$  sensors, along with their respective operating temperatures.

An innovative solution involves employing femtosecond (fs) laser treatments. These treatments modify the surface morphology by producing well-organized and periodic geometrical features, commonly known as Laser Induced Periodic Surface Structures (LIPSS) [40], increasing the surface area-to-volume ratio and reducing the grain size [41,42]. Additionally, fs-laser treatments introduce surface defects and electronically active defect levels in the semiconductor bandgap [43], potentially enhancing the performance of gas sensors. Despite its widespread use to modify wettability, optical and electronic properties of the materials in different scientific fields [44-47], fs-laser treatments have not been studied for enhancing the sensitivity of thin films used as gas sensors. The ultra-short duration of the laser pulse minimizes heat-related damage, preserving the material's integrity. During treatment, rapid material redistribution leads to morphological and electronic changes. The key advantage of these treatments is their reproducibility and efficiency, potentially facilitating their adoption as a standardized industrial process and significantly reducing costs.

The proposed  $\text{SnO}_2$ -based gas sensor, designed to enhance  $\text{CO}_2$  detection at room temperature, was morphologically characterized using scanning electron microscopy (SEM). Surface roughness and area were analysed with atomic force microscopy (AFM). Raman spectroscopy (RS) and X-ray photoelectron spectroscopy (XPS) techniques were employed for structural and elemental analysis. Following this, the thin film was treated with a fs-laser, and its  $\text{CO}_2$  gas sensitivity was tested at room temperature.

## 2. Experimental section

### 2.1. Films Deposition by Electron Beam Evaporation

Thin films of tin oxide were deposited on printed-circuit board (PCB) alumina substrates (thickness: 1 mm, produced by CERcuits BV, Geel, Belgium) using electron beam deposition, starting from SnO<sub>2</sub> pellets (Mateck GmbH, purity 99.95%) as target materials. The deposition was performed in a high vacuum chamber evacuated to a base pressure of approximately  $1 \times 10^{-6}$  mbar. The SnO<sub>2</sub> pellets were held in a Al<sub>2</sub>O<sub>3</sub> crucible (Kurt J. Lesker Company GmbH, Dresden, Germany) and evaporated by an electron beam with a kinetic energy of 5.75 keV and a current of 40 mA, controlled through an electromagnetic lens system to ensure a homogeneous deposition process. During deposition, the chamber pressure was maintained at approximately  $1 \times 10^{-4}$  mbar. Due to the large roughness of the alumina substrate, a thickness of 1  $\mu$ m was chosen as the thinnest option, ensuring both complete and uniform coverage. To allow fine control over the process and limited uncontrolled kinetics and poorer quality thin film properties, the e-beam deposition rate was kept to 1 nm/s. Moreover, the thickness of the film was controlled during the deposition through a calibrated quartz microbalance that allowed to accurately deposit the chosen thickness of material, inducing a shutter to close when the nominal thickness of 1  $\mu$ m was reached. The thickness of the deposited film was then verified by AFM profile analysis. The roughness average (Ra) parameter representing the surface roughness, derived from AFM scans (shown in detail in the next section), was used to quantify the excursion from the thickness across the surface. This procedure leads to the film thickness estimation of  $1.000 \pm 0.067$   $\mu$ m. Furthermore, as described in detail in the next sections, this film appears to be completely covered by an ultra-thin non-stoichiometric SnO<sub>2</sub> layer (< 10 nm), creating a p-n junction at the interface. The schematic illustration of the sensor is shown in Figure 1.

## 2.2. Structure and Morphology Characterization

The morphology of the SnO-SnO<sub>2</sub> thin films has been investigated by Field-Emission Gun Scanning Electron Microscopy (FEG-SEM- Zeiss Leo Supra 35, Germany) and by AFM carried out with use of an OmegaScope platform (HORIBA Ltd., Kyoto, Japan). AFM imaging was performed in tapping mode, setting the operational amplitude at 60 nm, and using a silicon pyramidal tip (MikroMasch HQ:NSC15/Al BS; Wetzlar, Germany) with a characteristic radius of ~8 nm. The resonance frequency was 325 kHz. The scan rate was fixed at 0.5 Hz. All the AFM data were acquired, filtered, and analysed using the AIST-NT.v3.5. SPM control software. Raman measurements were carried out using a Horiba Scientific LabRam HR Evolution confocal spectrometer equipped with a 100 mW Oxxius ( $\lambda_{\text{exc}} = 532$  nm) laser source and a computerized XY-table, an electron-multiplier CCD detector, and an Olympus U5RE2 microscope with a 100x objective (laser spot on the sample surface 0.7  $\mu$ m) with a numerical aperture (NA) of 0.9, and a grating with 1800 grooves/mm were used. All Raman spectra were recorded in backscattering geometry focalizing 10% of the laser sources power at the sample and ten spectra with an accumulation time of 10 s were averaged. XPS enabled the investigation of the composition of the SnO-SnO<sub>2</sub> thin films before and after the fs-laser treatment, and it was carried out by using a spectrometer ESCALAB 250 Xi (Thermo Fisher Scientific Ltd., East Grinstead, UK), equipped with a monochromatic Al K $\alpha$  source ( $h\nu = 1486.6$  eV) and a hemispherical analyzer with six-channeltron as the detection system. The XPS measurements were performed operating in an ultra-high vacuum chamber at a base pressure of about  $8 \times 10^{-9}$  mbar. The binding energy (BE) scale was calibrated by positioning the C 1s adventitious carbon peak at BE = 284.8 eV, with an accuracy of  $\pm 0.1$  eV. The spectra were collected and processed by Avantage software v.5.9 (Thermo Fisher Scientific, East Grinstead, UK)

## 2.3. Laser Treatment

The surface nanotexturing process was carried out using a Ti:Sapphire femtosecond laser (Spectra-Physics, Milpitas, CA, USA) with the following characteristics: pulse duration of 100 fs, linear polarization, laser wavelength ( $\lambda$ ) of 800 nm, repetition rate of 1 kHz (corresponding to 1 ms of time delay between two generated pulses). The laser beam was generated by a mode-locked oscillator and subsequently regeneratively amplified. The laser impinged the surface following a boustrophedonic movement (i.e., scanning a surface line by line, horizontally from left to right, and then the next line below moving from right

to left). This pattern repeats until the entire area is covered (the LIPSS fabrication is extended to the entire thin film area covering the alumina PCB with deposited area of approximately 20x20 mm<sup>2</sup>). This method minimizes the time spent repositioning between lines. Pulses were perpendicularly focused in air by an objective lens (4x, N.A. = 0.10) onto the surface of the thin film. The samples were moved by an automated X-Y translational stage ( $\mu$ FAB Microfabrication Workstation, Newport, CA, USA). The laser spot size was evaluated *a posteriori* through the use of scanning electron microscopy (SEM) following the methodology illustrated in Ref. [48]. The method permits to assess the  $1/e^2$  Gaussian beam diameter. The estimated diameter is approximately 100  $\mu$ m.

After preliminary testing, not showed in this paper for the sake of brevity, the laser pulse energy used was 4.5  $\mu$ J to obtain regular and homogeneous LIPSS. In scanning mode, the number of overlapping pulses per unit area is controlled by adjusting the scanning speed, denoted as  $v$ , following the relationship  $N = wf/v$ , where  $f$  is the laser repetition rate and  $w$  is the laser diameter on the focal spot. The selected scanning speed was 3000  $\mu$ m/s.

#### 2.4. Gas Sensing

The CO<sub>2</sub> sensitivity tests were conducted on SnO-SnO<sub>2</sub> thin films (the receptor part of the sensor) deposited on an alumina PCB, both before and after fs-laser treatment. The substrate type was selected for microelectronics applications because of its excellent thermal conductivity, mechanical strength, low dielectric constant, and minimal dielectric loss. To transduce the surface interaction of the film with CO<sub>2</sub>, two copper (Cu, 35  $\mu$ m) electrodes were deposited onto the substrates with a minimum inter-electrode gap of 10  $\mu$ m. A dedicated connector was soldered directly to these contacts, facilitating an easy push-and-pull connection to the signal conditioner. The gas sensor tests were conducted in a commercial glove box (Cole-Parmer Instrument Company, LLC, UK) with a volume of approximately 0.25 m<sup>3</sup>. The glove box allowed for monitoring and controlling the temperature and humidity throughout the tests, which were maintained at 20°C and 50  $\pm$  5%, respectively, to simulate typical comfortable indoor conditions. Additionally, the glove box maintained confined gas concentrations, with various CO<sub>2</sub> concentration levels achieved by mixing balanced CO<sub>2</sub> with dry air. The methodology for measuring gas sensitivity followed the same procedure as in our previous work [18]. Specifically, thanks to the use of a customized fluxmeter (IONVAC Process srl, Pomezia, Italy), it was possible to regulate the flow of CO<sub>2</sub> in the chamber, which was evacuated by a membrane pump (pressure of  $\sim 10^{-1}$  mbar) to ensure stable conditions and rapid gas removal. The current measurements were carried out by connecting the sensor to an electrometer (Keithley 487 Picoammeter/Voltage Source), with data recorded automatically through the management of the signals using the GPIB protocol and software specifically developed in LabVIEW (National Instruments, Austin, TX, USA).

### 3. Results and Discussion

The thin films obtained by electron beam deposition from SnO<sub>2</sub> pellets were morphologically characterized using SEM. SEM micrographs show that the alumina's morphology significantly influences the film's morphology. Despite being covered by approximately 1  $\mu$ m of tin oxides, the large crystalline grains of alumina remain visible (see SEM images, Figure 2a,b). This makes it difficult to assess the film's uniformity solely from SEM images. The same issue applies to the AFM image (Figure 2c). Only the higher resolution AFM image provides weak evidence of the presence of the deposited film, showing a rough layer with tiny grains over the alumina (refer to Figure 2d). AFM analysis was also used to assess surface roughness and estimate the surface area. Hence, the presence of the film is confirmed by changes in roughness parameters and the estimated surface area obtained from the analyses of 15  $\mu$ m x 15  $\mu$ m as scanned area and 500 x 500 pixels as lateral resolution images. After film deposition, the roughness values  $R_a$  and  $R_{ms}$  increased from 62.3 nm to 67.6 nm and from 78.1 nm to 85.2 nm, respectively. The surface area increased from 231.9  $\mu$ m<sup>2</sup> to 247.1  $\mu$ m<sup>2</sup>, as reported in Table 2 (the values were estimated by the use of AIST-NT.v3.5. software).

After deposition, the sample was subjected to the fs-laser irradiation. As explained above, the choice to apply fs-laser treatment was driven by its capability to modify surface morphology to induce a texturing of the surface microstructure by creating so-called Laser-Induced Periodic Surface Structures (LIPSS), which increase surface area and provide more active sites for gas adsorption [49]. Additionally, the laser treatment could also change the surface chemistry, by adding oxygen vacancies during localized heating and rapid cooling, which can act as active site for CO<sub>2</sub> adsorption. These phenomena could lead to enhanced electronic properties, such as reduced resistance and improved charge carrier mobility, leading to more intense signal responses and faster reaction times. These mechanisms could be promising especially for improving the sensor's selectivity and response at RT, overcoming the need for elevated temperatures (300-350 °C) traditionally required by SnO<sub>2</sub>-based sensors. The morphological alterations are clearly visible under scanning microscopy (see Figure 3 a,b), which shows the emergence of the LIPSS with a spatial periodicity of  $\Lambda = 750 \text{ nm} \pm 50 \text{ nm}$ , as estimated using the 2D-FFT transformation method. The 2D-FFT transformation of a large-area SEM image (45  $\mu\text{m} \times 65 \mu\text{m}$ ) and the corresponding intensity signal profile are shown in Figures 3e and 3f, respectively. This periodicity aligns with the Ti: Sapphire femtosecond laser wavelength used (800 nm), confirming the condition  $\Lambda = \lambda_{\text{fsr}}$ , as expected for metals and narrow bandgap semiconductors [50] such as SnO [26,51]. Similarly, roughness and surface area parameters were evaluated through AFM analysis (Figure 3 c,d). Following laser treatment, the roughness parameters Ra and RMS exhibited significant increases from 67.6 nm to 272.0 nm and from 85.2 nm to 303.0 nm, respectively. Likewise, the surface area value surged from 247.1  $\mu\text{m}^2$  to 285.1  $\mu\text{m}^2$ . A summary of the comparison between all roughness parameters and surface area values is presented in Table 2.

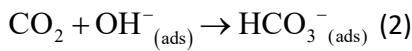
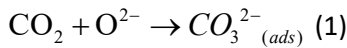
The Raman and XPS spectrometric analyses provide comprehensive insights into the structure and composition of the as-deposited films. Regarding Raman spectroscopy, two bands, B1g = 112  $\text{cm}^{-1}$  and A1g = 210  $\text{cm}^{-1}$  attributable to the SnO species, are observed, in addition to the signals related to the alumina substrate. This is in perfect agreement with the literature [51-56]. However, the typical band of SnO<sub>2</sub>, centered at approximately 470  $\text{cm}^{-1}$ , is not present (see Figure 4). Nonetheless, this observation is in contrapositions by the XPS results, which is an extremely surface-sensitive technique, where the peaks of Sn 3d<sub>5/2</sub> at BE= 486.6 eV and O 1s at BE= 530.8 eV indicate the presence of Sn<sup>+4</sup> oxidative state, corresponding to the SnO<sub>2</sub> upper coatings [27,57-60] (all the fitted photoemission peaks are shown in Figure 5). Not only the XPS photoemission peaks, but also the valence band signal (see Figure 6) confirms the presence of the SnO<sub>2</sub> surface termination showing the typical shape reported in the literature [60]. The main photoemission peaks, XPS at. % quantification, and corresponding chemical bonds of the thin film, both as deposited and after fs-laser treatment, are summarized in Table 3. The Sn/O ratio (both taking into account only -B signals) is 0.6. This suggests a slight deviation from the stoichiometric value of SnO<sub>2</sub>, indicating an excess of Sn. This disproportion could arise from the presence of small quantities of SnO, which may generate crystal defects. From the Raman spectroscopy conducted on the fs-laser treated sample, it emerges that there is no substantial modification of the structure after the laser treatment, as the observed peaks remain the same as those before the treatment. However, the signals appear narrower and more defined, suggesting that the laser treatment induces a more ordered and homogeneous recrystallization of the materials on the alumina substrate. On the other hand, XPS characterization highlights a decrease in the percentage of SnO<sub>2</sub> (from 20.9 at. % to 12.4 at. %) in favour of SnO (from negligible amount to 18.6 at. %). This is also evident from the shift and shape modification of the valence band spectra (Figure 6), confirming that the laser treatment reduces the terminal part of SnO<sub>2</sub> present on the surface of the film [57-60], resulting in a more ordered structure as evidenced by Raman spectroscopy.

Therefore, the complete compositional and structural study suggests the formation of a native SnO-SnO<sub>2</sub> structure, which can act as an active p-n junction at the interface due to the different electronic properties of the two materials. The fs-laser treatment induces a modification of the surface, by decreasing the quantity of SnO<sub>2</sub> species and forming a more complex SnO-SnO<sub>2</sub>/SnO structure. As reported in previous studies, forming a p-n junction is an effective strategy to enhance the performance of chemiresistor gas sensors [10, 25-27]. Specifically, the heterostructures formed between p-SnO and n-SnO<sub>2</sub> are crucial for improving gas sensing response at low temperatures compared to pure SnO<sub>2</sub> thin films. In fact, the junction of two materials

with different work functions such as p-SnO and n-SnO<sub>2</sub> can create a region with an enhanced charge carrier density. This can lead to higher electron or hole mobility at low temperature, improving the sensitivity of the sensor to gases by decreasing the operating temperatures even at room temperature [61]. Moreover, the narrower valence band offsets of these heterojunctions reduce the energy required for electron transitions [26,27]. In other words, the charges present on the SnO-SnO<sub>2</sub> surface make these heterostructures more effective at attracting CO<sub>2</sub> gas than pure SnO<sub>2</sub> at room temperature.

The oxygen and the water molecules present in humid air interact with surface of the film forming ionized oxygen species (O<sup>2-</sup>, O<sup>-</sup>) and hydroxyl ions, oxygen vacancies and electrons, respectively [62-64].

Exposing the SnO-SnO<sub>2</sub> to the CO<sub>2</sub> gas, it reacts with and the O<sup>2-</sup> and hydroxyl species pre-adsorbed on film surface, releasing bicarbonate and carbonate ions, described in following chemical reactions (1,2) [65]:



Similar to pure SnO<sub>2</sub>, this gas sensing mechanism leads to increase the device's resistance due to the reduction of accumulation layer hole concentration [61].

Furthermore, the SnO-SnO<sub>2</sub> p-n heterostructures show higher responses because, in addition to interacting with the chemisorbed oxygen, they can directly adsorb CO<sub>2</sub> molecules onto the surface by extracting electrons from the conduction band [26,27].

Concerning the effect of the laser treatment, it is possible to state that such formed p-n junction is compromised after the nanostructuring process, as XPS analysis shows a decrease in the presence of SnO<sub>2</sub> (see Table 3). The reduction of upper SnO<sub>2</sub> coating reduces the benefits offered by the heterostructure regarding sensitivity to CO<sub>2</sub> at room temperature, as will be described later in this paragraph. Nevertheless, the investigation of electrical material stability showed that the fs-laser treated film exhibits significantly higher stability compared to the untreated one. When left in the air for a day, it stabilizes at a consistent resistance value much faster than the untreated material, which shows more pronounced resistance fluctuations over the same period (see Figure. 7).

Once the sensor stabilized, sensitivity tests to CO<sub>2</sub> were conducted on the as-deposited sample. Initially, a calibration curve was generated and the sensor appears to respond linearly to the CO<sub>2</sub> concentrations in the range from 110 to 5000 ppm (Figure 8) (In the range of values between 0 and 110 ppm, the gas response was not tested due to limitations in the experimental setup. Therefore, the linearly fitting calibration curve shown in Figure 8 applies only to concentrations above 110 ppm). Outdoor CO<sub>2</sub> levels typically range from 350-400 ppm, while indoor environments typically aim for a maximum of 1500 ppm. Values exceeding 1500 ppm may lead to initial negative effects such as headaches, with significant health risks emerging around 5000 ppm, including nausea and increased heart rate [1]. The sensing response R (%) of the sensor was estimated by the equations (3) [61]:

$$(3) \quad R (\%) = \frac{(R_{\text{gas}} - R_{\text{air}})}{R_{\text{air}}} \times 100$$

Where the R<sub>gas</sub> and R<sub>air</sub> are the measured resistance before and after the CO<sub>2</sub> gas exposure. Regarding the sensitivity (S), it was estimated by the slope of the linear fitted curve of the sensing response, i.e. from equation (4) (see Figure 8) [58,66]:

$$R(\%) = S * [CO_2] + R_{air} \quad (4)$$

Where  $[CO_2]$  is the gas concentration.

The sensor demonstrates excellent sensing response within the concentration range of 1000 to 2000 ppm, showing  $R(\%)$  levels ranging from 7% to 20%. Notably,  $R(\%)$  increases to ~40% around the critical concentration of 5000 ppm (see Figure 8). Therefore, the as-deposited gas sensors show highly sensitive response values, that can be attributed to the action of the p-n SnO-SnO<sub>2</sub> heterojunction formed natively with the e-beam deposition. Indeed, the evaluated sensitivity was found to be 0.008 %ppm<sup>-1</sup>.

Then, multiple consecutive cycles were repeated at a CO<sub>2</sub> concentration of 5000 ppm. What is observed is that the sensitivity remains at high values even after some cycles. Additionally, the sensor response time and recovery time were calculated to be about 1 s and 2 minutes, respectively (Fig. 9).

Conversely, the response of the femtosecond laser-treated sensor exhibits a peculiar behaviour that needed further investigation. It shows a "stepwise progression", meaning that the sensor's resistance value increases by the same amount for each cycle, never returning to its initial value. In other words, although the treated material displays a very short response time, the recovery time is infinite, meaning the sensor never returns to its initial conditions. Despite this, the resistance increments for each cycle are constant, i.e., the resistance increases by a constant amount for each cycle. The difference in surface properties between the untreated and treated materials likely explains this phenomenon. A notable distinction lies in the presence of the non-stoichiometric n-type SnO<sub>2</sub> terminal layer, which is considerably less prevalent in the treated film in favour of the appearance of a more pronounced quantity of SnO reduced oxidation state. This hypothesis gains support from the spatial periodicity of the LIPSS, which corresponds to 780 nm, similar to the laser wavelength used for the fs-laser treatment (800 nm). This correspondence suggests a predominance of microstructured SnO covered by a thinner and inhomogeneous SnO<sub>2</sub> layer, which has however an active role in the gas detection. In fact, SnO interacts with the laser to produce structures with a periodicity that satisfies the condition  $\Lambda = \lambda_{fs}$ , as expected for metals and semiconductors with a narrow band gap such as SnO [50]. In contrast, if SnO<sub>2</sub> had been predominant, the treatment would have produced LIPSS at a high spatial frequency, with a periodicity  $\Lambda \leq \lambda_{fs} / 2$ , typical of wide bandgap semiconductors, as observed in a previous work by D. Scortitica et al. [67]. Consequently, the laser-treated material exhibits more p-type SnO behaviour, resulting in a lower value of the sensor's resistance before the gas exposure. Indeed, the equilibrium resistance value in air shifts from approximately 10<sup>9</sup> Ω for the untreated (as-deposited) film to around 10<sup>7</sup> Ω for the treated material, representing a starting value less than 100 times smaller.

When the surface of the fs-laser treated material interacts with CO<sub>2</sub>, oxidation of SnO into SnO<sub>2</sub> may occur, initiating an irreversible chemical reaction and establishing a new equilibrium state with each CO<sub>2</sub> exposure cycle. This also explains why an increase of resistance was recorded when the sensor is exposed to the gas, as typically occurs for n-type materials. Over successive CO<sub>2</sub> cycles, the material's resistance will gradually increase until all oxygen vacancies on the surface are saturated.

Despite the irreversible changes induced by CO<sub>2</sub> on the treated film, multiple consecutive cycles were conducted to assess the sensor's sensitivity after numerous exposures to the gas. To facilitate this evaluation, the resistance  $R$  ratio value was calculated (Figure 10). For the as-deposited film, it was simply computed as  $R/R_0$ , while it was the value of the step-by-step variation (i.e.,  $R_n\text{-cycle}/R_{n-1}\text{ cycle}$ ) for the treated film.

By analyzing the slope of these plots, the cycle number at which the ratio becomes  $> 1.02$  (considering 2% as the detection limit of the signal with respect to the background) was extrapolated. This threshold indicates when the sensor remains sensitive to the gas. Through this approach, we could estimate that both sensors remain sensitive to the gas ( $R > 1.02$ ) for more than 30 cycles. This indicates that both sensors exhibit the good sensitivity threshold, despite the treated sensor initially displaying lower sensitivity compared to the untreated sensor.

Figure 11 shows the different structures involved in the gas sensing mechanism. It seems reasonable to assume that before laser treatment, the sensor's primary mechanism is driven by the p-n heterojunction between SnO and SnO<sub>2</sub> which allow the sensor to operate at RT. After laser treatment, the main sensing role is played by the surface nanostructuring that enhances the surface area, active sites, and oxygen vacancies, improving CO<sub>2</sub> interaction. In this case, the sensing mechanism is different due the significantly reduced SnO<sub>2</sub> layer, with a response like a "stepwise progression" in the change of resistance, which is somewhat different for this kind of devices. Indeed, the presence of LIPSS could stimulate an enhanced sensing with the increased surface area, but, at the same time, trap the chemical species by getting unavailable the active sites for restoring the native surface. In any case, the fs-laser engineering and functionalization of the surface result in promising performance for the sensor in terms of signal stability, reproducibility, and RT operations.

These findings demonstrate the effectiveness of the SnO<sub>2</sub>-based CO<sub>2</sub> sensor for real-world applications, particularly in promoting health and safety compliance in confined spaces with a high human occupancy or CO<sub>2</sub> production. Compared to Non-Dispersive Infrared (NDIR)-based commercial CO<sub>2</sub> sensors, the devices developed in this work are more stable in ambient condition, cost-effective and easily integrated into miniaturized systems, while maintaining comparable performance in terms of sensitivity, recovery time, and device lifespan [68]. Operating efficiently at RT, the sensor shows significant potential for indoor air quality monitoring in smart building systems, HVAC (Heating, Ventilation, and Air Conditioning) systems, and environmental monitoring. Its energy-efficient operation, without the need for high-temperature activation, makes it ideal for homes, offices, and industrial spaces. This sensor can play a key role in IoT-based building management by collecting data on air quality, energy usage, and meteorological conditions. Such capabilities support real-time, cloud-based control of indoor environments, enhancing energy efficiency, comfort, and safety in both residential and commercial buildings.

## Conclusions

The CO<sub>2</sub> sensing performance of SnO-SnO<sub>2</sub> heterojunctions formed by depositing thin films on alumina PCB with electron beam evaporation was tested at room temperature for both as-deposited and after fs-laser treated sensors. The untreated SnO-SnO<sub>2</sub> film showed a sensing response ranging from 7% to 20% for CO<sub>2</sub> concentrations of 1000 to 2000 ppm, and up to 40% at the hazardous concentration of 5000 ppm. The formation of a p-n junction between SnO and SnO<sub>2</sub> significantly enhances the sensor's response. Despite the fs-laser modified the surface by improving the morphological features, as shown by SEM and AFM, the treated sensors did not show an improved response. However, they demonstrated good performance to detect CO<sub>2</sub> in terms of response stability, also showing a different behaviour in the gas sensing mechanism with respect to conventional MOX-based sensors. This could be exploited for specific applications in which a high stability and fast conditions to reach it are requested. Therefore, the fs-treatment represents a novel approach for modifying MOX gas sensor materials to operate effectively as fast sensor at room temperature, offering the potential for a standardized industrial process for their production.

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**Fig. 1.** Schematic illustration of SnO-SnO<sub>2</sub> based gas sensor.

**Fig. 2.** SEM micrographs (a, b) and AFM topographies (c,d) of SnO-SnO<sub>2</sub> films as deposited on Al<sub>2</sub>O<sub>3</sub> substrate at different magnifications.

**Fig. 3.** SEM micrographs (a, b) and AFM topographies (c,d) of SnO-SnO<sub>2</sub> films on Al<sub>2</sub>O<sub>3</sub> substrate after fs-laser treatment at different magnifications. 2D-FFT transformation of a large area (45 µm x 65 µm) SEM image (e) and intensity signal profile (f).

**Fig. 4.** Raman spectra of bare Al<sub>2</sub>O<sub>3</sub> substrate, SnO-SnO<sub>2</sub> film as deposited and after fs-laser treatment.

**Fig. 5.** Peak fitting of Sn 3d<sub>5/2</sub>, O 1s, C1s of SnO-SnO<sub>2</sub> thin film as deposited and after fs-laser treatment

**Fig. 6.** Comparison of XPS valence band spectra of SnO-SnO<sub>2</sub> thin film as deposited and after fs-laser treatment

**Fig. 7.** Comparison between electrical material stability for as deposited and fs-laser treated SnO-SnO<sub>2</sub> thin films.

**Fig. 8.** Calibration curve in the range 110-5000 ppm of CO<sub>2</sub> concentration.

**Fig. 9.** Sensing response repeatability and recovery time characterization at 5000 ppm of CO<sub>2</sub> exposure for as deposited (a) and fs-laser treated (b) film.

**Fig. 10.** R ratio value for as deposited (blue line) and fs-laser treated (red line) film.

**Fig. 11.** Schematic illustration of gas sensing mechanism before and after the fs-laser treatment.

**Table 1.** SnO<sub>2</sub>-based CO<sub>2</sub> sensors

| Materials           | Method/structure                        | Operating Temperature (°C) | [CO <sub>2</sub> ] (ppm) | Response/Recovery Times (s) | References | Year |
|---------------------|-----------------------------------------|----------------------------|--------------------------|-----------------------------|------------|------|
| SnO <sub>2</sub>    | Co-precipitation/<br>Nanoparticles      | 240                        | 2000                     | 350/4                       | [28]       | 2016 |
| Ni-SnO <sub>2</sub> | microwave-<br>irradiation/nanoparticles | 275                        | 100                      | 4/-                         | [22]       | 2020 |

|                                                     |                                                            |         |                 |             |      |      |
|-----------------------------------------------------|------------------------------------------------------------|---------|-----------------|-------------|------|------|
| 8at% LaOCl-SnO <sub>2</sub>                         | Electrospinning/Nanofibers                                 | 300     | 1000            | 24/92       | [29] | 2017 |
| SnO <sub>2</sub> @ZIF-67                            | Mixing Core-shell                                          | 205     | 5000            | 220/25      | [30] | 2018 |
| LaFeO <sub>3</sub> -SnO <sub>2</sub>                | Mixing Porous powders                                      | 250     | 4000            | <20/-       | [31] | 2017 |
| 5wt%Sn-CdO                                          | Coprecipitating /Nanopowders                               | 250     | 5000            | 110/140     | [32] | 2015 |
| SnO <sub>2</sub> @La <sub>4</sub> at%               | Impregnation/Nanoparticles                                 | 250/N2  | 500             | 20/75       | [33] | 2014 |
| Sb@SnO <sub>2</sub>                                 | sol-gel spin coating/Thin film                             | 30-80   | -               | <12/<10     | [21] | 2022 |
| Au@La <sub>2</sub> O <sub>3</sub> /SnO <sub>2</sub> | Electrospinning/<br>nanofibers                             | 300     | 100             | -           | [34] | 2020 |
| SnO <sub>2</sub>                                    | Co-precipitation                                           | 240     | 20000           | 31/47       | [28] | 2016 |
| La@SnO <sub>2</sub>                                 | Hydrothermal and<br>impregnation /nanoparticles            | 250     | 500             | 30/75       | [33] | 2014 |
| La@SnO <sub>2</sub>                                 | Electrospinning/nanofibers                                 | 300     | 1000            | -           | [29] | 2017 |
| La <sub>2</sub> O <sub>3</sub> @SnO <sub>2</sub>    | MHP/layer                                                  | 400     | 1000            | -           | [36] | 2017 |
| Sb@SnO <sub>2</sub>                                 | Solution<br>combustion/Nanoparticles                       | 350     | 1000            |             | [37] | 2022 |
| Sb@SnO <sub>2</sub>                                 | Sol-gel spin coating/Spherical<br>particles                | 30      | -               | 2.5/5.8     | [21] | 2022 |
| SnO <sub>2</sub> /rGO                               | Reduction/nanocomposite film                               | 23      | 5               | 41/47       | [38] | 2021 |
| Pt@La <sub>2</sub> O <sub>3</sub> /SnO <sub>2</sub> | Screen-printing/thick film                                 | 225     | 1000            | -           | [39] | 2016 |
| Nano-SnO <sub>2</sub>                               | nano-powders annealed/<br>nanothick-films                  | 23      | 2000 to<br>4000 | 10-350/4-54 | [28] | 2016 |
| ZnO doped SnO <sub>2</sub><br>films                 | spray deposited/<br>nanocrystalline SnO <sub>2</sub> films | 270-310 | 500             | 40/32       | [29] | 2017 |

|                                       |                                                  |    |             |       |           |      |
|---------------------------------------|--------------------------------------------------|----|-------------|-------|-----------|------|
| SnO-SnO <sub>2</sub>                  | e-beam/thin films heterojunction                 | 20 | 110 to 5000 | 1/120 | This work | 2024 |
| SnO-SnO <sub>2</sub> fs-laser treated | e-beam + fs.laser treatment / thin films + LIPSS | 20 | 110 to 5000 | 1/-   | This work | 2024 |

**Table 2.** AFM Roughness parameters: comparison between Ra and RMS and surface areas for bare alumina substrate and SnO-SnO<sub>2</sub> thin films as deposited and after fs-laser treatment.

|                                 | Bare Al <sub>2</sub> O <sub>3</sub> | SnO-SnO <sub>2</sub> as deposited | SnO-SnO <sub>2</sub> after fs-laser treatment |
|---------------------------------|-------------------------------------|-----------------------------------|-----------------------------------------------|
| R <sub>a</sub> (nm)             | 62.3                                | 67.6                              | 272                                           |
| RMS (nm)                        | 78.1                                | 85.2                              | 303                                           |
| Surface Area (μm <sup>2</sup> ) | 231.9                               | 247.1                             | 284.1                                         |

**Table 3.** Main photoemission peaks, at. % quantification and corresponding chemical bond of SnO- SnO<sub>2</sub> thin film as deposited and after fs-laser treatment.

|         | As deposited SnO- SnO <sub>2</sub> |       |      | After fs-laser treatment |       |      |
|---------|------------------------------------|-------|------|--------------------------|-------|------|
| Peak    | BE (eV)                            | At. % | Bond | BE (eV)                  | At. % | Bond |
| C1s - A | 284.8                              | 10.7  | C-C  | 284.8                    | 18.7  | C-C  |
| C1s - B | 286.3                              | 3.5   | C-O  | -                        |       | -    |
| C1s - C | 288.8                              | 7.5   | -C=O | 288.4                    | 3.9   | -C=O |
| O1s - A | -                                  |       |      | 529.3                    | 19.9  | SnO  |

|           |       |      |                                            |       |      |                                            |
|-----------|-------|------|--------------------------------------------|-------|------|--------------------------------------------|
| O1s - B   | 530.8 | 34.3 | SnO <sub>2-x</sub>                         | 530.9 | 18.5 | SnO <sub>2-x</sub>                         |
| O1s - C   | 532.2 | 15.9 | O <sub>chemisorbed</sub> , OH groups, -C=O | 532.5 | 8.0  | O <sub>chemisorbed</sub> , OH groups, -C=O |
| O1s - D   | 533.4 | 4.1  | H <sub>2</sub> O                           | -     | -    | -                                          |
| Sn3d5 - A | -     | -    | -                                          | 485.5 | 18.6 | SnO                                        |
| Sn3d5 - B | 486.6 | 20.9 | SnO <sub>2-x</sub>                         | 487.4 | 12.4 | SnO <sub>2-x</sub><br>(nanostructured)     |
| Sn3d5 - C | 488.3 | 3.0  | Sn hydroxide                               | -     | -    | -                                          |